ELSEVIER

Thin Solid Films 353 (1999) 283–284

thin solid films

Author Index of Volume 353

Aguilar, M., 1
Amin, S., 149
Anderson, J., 218
Armstrong, N.R., 218
Attanasio, C., 227
Ayupov, B.M., 79

Bai, H.L., 157
Barnard, J., 16
Bayón, R., 100
Bienfait, S., 93
Birch, J., 166
Blachere, J., 16
Boussaad, S., 233
Brown, I.G., 239

Caballero, A., 113
Ceh, O., 1
Charitidis, C., 208
Chen, G.S., 264
Chen, P.-S., 274
Chen, S.T., 264
Chen, X.Q., 259
Chu, C.-H., 274
Chu, H.-S., 174
Cleymand, F., 194
Contreras, L., 113
Corona, J.E., 1
Coupeau, C., 194

Di Luccio, T., 227
Ding, Y., 218
D'Iorio, M., 218
Dodelet, J.P., 218
Dolgpvesova, I.P., 79
Dugnoille, B., 93
Dultsev, F.N., 108
Dumont, E., 93

Eby, R., 149
Espinós, J.P., 113

Fan, X., 223
Fernández, A., 113
Fischer, Ø., 62
Fleming, J.G., 149
Flinn, P.A., 201
Freyhardt, H.C., 33
Fujimoto, H., 201

Gabrielli, G., 214
Galewski, C.J., 149
Gan, F., 40
Gauvin, S., 218
Gokce, O.H., 149
González-Elipe, A.R., 113
Gorjanc, T.C., 218
Goudeau, P., 194
Graat, P.C.J., 72
Grilhé, J., 194
Gritsenko, V.A., 20
Guilloux-Viry, M., 62
Gusso, M., 129
Guttmann, P., 33

Halvarsson, M., 182
Han, S.-Y., 45
Hao, X., 223
Hartung, F., 33
Hay, A.S., 218
Heinemann, K., 33
Herrero, J., 100
Hillebrands, B., 137
Hlil, A.R., 218
Ho Cho, M., 8
Hoffmann, J., 33
Horiuchi, T., 259
Hou, L., 40
Hsieh, T.E., 274
Hwang, C.-C., 174
Hyo Lee, C., 12

Ignat, M., 201
Inturi, V., 16
Inui, Y., 189

Jiang, E.Y., 157
Jiménez, V.M., 113
Johansson, M.P., 166
Jorzick, J., 137
Jung, K., 137
Justo, A., 113

Kang, S.-K., 8
Kim, E.-H., 8
Kitchay, V.N., 79
Klemmer, T.J., 16
Ko, D.-H., 8
Krishna Pillai, M.G., 249
Kugler, M., 62
Kumagai, T., 52
Kumazawa, H., 144
Kwok, R.W.M., 20

Leblanc, R.M., 233
Lee, P.Y., 264
Lee, S., 45
Lee, S.-G., 244
Lee, Y.-H., 244
Lemée, N., 62
Li, B., 56
Li, Z.Z., 62
Lin, C., 25
Lin, S., 174
Liu, X., 56
Liu, Y., 124
Logothetidis, S., 208
Lokhande, C.D., 29
Lu, S., 40
Luo, J., 56

Maffiotte, C., 100
Mammana, V.P., 239
Manabe, T., 52
Mane, R.S., 29
Mansano, R.D., 239
Marieb, T., 201
Maritato, L., 227
Masuda, K., 144
Matsushige, K., 259
Miao, W., 56
Milov, A.D., 20
Minor, K., 16
Mitsas, C.L., 85
Mittemeijer, E.J., 72
Mizukami, F., 67
Mizuta, S., 52

Nadolinny, V.A., 79
Nagahama, T., 52
Nakaaki, I., 189
Naud, J.F., 194
Nishide, T., 67

Oh, S.-G., 45
Oliva, A.I., 1

Paff, R.J., 149
Pavani Filho, A., 239
Penza, M., 129
Perrin, A., 62
Polychroniadis, E.K., 85
Prischepa, S.L., 227

Quintana, P., 1
Quirini, A., 129

Raffy, H., 62
Rajagopalan, T., 254
Ravindra, N.M., 149
Reddy, G.B., 254
Ren, W., 25, 124
Ricceri, R., 214
Rudolph, D., 33
Ruppi, S., 182

Saito, N., 189
Sakthi Kumar, D., 249
Salluzzo, M., 227
Salvadori, M.C., 239
Salvato, M., 227

PII: S0040-6090(99)00666-5

Sandström, P., 166
Sankapal, B.R., 29
Santerre, F., 218
Schmitz, G., 33
Shallenberger, J., 149
Silva, S., 239
Smirnova, T.P., 79
Somers, M.A.J., 72
Song, Z.-T., 25
Sundgren, J.-E., 166
Svedberg, E.B., 166
Szostak, D.J., 149

Taeg Lim, W., 12
Tagliente, M.A., 129
Tao, K., 56
Tazi, A., 233
Terai, Y., 259
Thieme, J., 33
Thomas, J., 16
Troche, P., 33
Tsuchiya, T., 52

Vasilyeva, L.L., 108
Verdonck, P., 239

Wang, M., 223
Weiss, P.S., 259
Whang, C.N., 8
Wittkowski, T., 137
Wong, H., 20

Xu, J.B., 20

Yakovkina, L.V., 79
Yamada, H., 259
Yamaguchi, I., 52
Yamaguchi, T., 189
Yao, X., 25, 124

Zhang, L., 124
Zhang, L.-Y., 25
Zhuravlev, K.S., 20

ELSEVIER

Thin Solid Films 353 (1999) 285–289

thin solid films

Subject Index of Volume 353

Adhesion
Mechanical behaviour of submicron multilayers submitted to microtensile experiments, 201
Air-annealing
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100
Aluminum
Current induced effects in aluminum thin films, 1
α - Al_2O_3
TEM investigation of wear mechanisms during metal machining, 182
κ-Al_2O_3
TEM investigation of wear mechanisms during metal machining, 182
Amorphous materials
New method for making porous SiO_2 thin films, 124
Indium doping of amorphous SiC:H films prepared by reactive magnetron co-sputtering, 189
Annealing
Improvement of the thermal stability of amorphous carbon films by incorporation of nitrogen, 157
Conduction mechanism in plasma polymerized lemongrass oil films, 249
Effect of annealing rate on the crystallization process in $Ge_5Bi_{18}Se_{77}$ films, 254
Atomic force microscopy
Current induced effects in aluminum thin films, 1
Atomic force microscopy of in situ deformed nickel thin films, 194
Strong substrate effect in local poling of ultrathin ferroelectric polymer films, 259
Auger electron spectroscopy
Surface analysis and phase transition of gel-derived VO_2 thin films, 40

Bismuth layer-structured ferroelectrics
Epitaxy of (106)-oriented $SrBi_2Ta_2O_9$ and $SrBi_2Nb_2O_9$ thin films, 52
Boron nitride
Elastic properties of thin *h*-BN films investigated by Brillouin light scattering, 137
Brillouin light scattering
Elastic properties of thin *h*-BN films investigated by Brillouin light scattering, 137
Buckling
Atomic force microscopy of in situ deformed nickel thin films, 194

Capacitors
Fabrication of barium titanate thin films with a high dielectric constant by a sol–gel technique, 144
Carbon
Elastic properties of hydrogen-free amorphous carbon thin films and their relation with carbon–carbon bonding, 208
Carbon nitride films
Improvement of the thermal stability of amorphous carbon films by incorporation of nitrogen, 157
Catalysis
The effect of catalyzing additives on Sol–gel process of formation and on the properties of modified polysiloxane layers, 108
Cd-free buffer layer
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100
Chalcogenide
Effect of annealing rate on the crystallization process in $Ge_5Bi_{18}Se_{77}$ films, 254
Characterization
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100
Chemical bath deposition
Non-aqueous chemical bath deposition of Sb_2S_3 thin films, 29
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100
Chemical vapor deposition
SnO_2 thin films prepared by ion beam induced CVD: preparation and characterization by X-ray absorption spectroscopy, 113
TEM investigation of wear mechanisms during metal machining, 182
Porous freestanding diamond membranes with reduced pore diameter, 239
Solid phase epitaxy for low pressure chemical vapor deposition Si films induced by ion implantation, 274
Clusters
Structural characterization of epitaxial $Cu_2Mo_6S_8$ thin films grown on *R*-cut sapphire by pulsed laser deposition, 62
Coating-pyrolysis process
Epitaxy of (106)-oriented $SrBi_2Ta_2O_9$ and $SrBi_2Nb_2O_9$ thin films, 52
Coatings
Fabrication of barium titanate thin films with a high dielectric constant by a sol–gel technique, 144
Conductivity
Conduction mechanism in plasma polymerized lemongrass oil films, 249

PII: S0040-6090(99)000665-3

Crystallization
Effects of annealing on X-ray-amorphous CVD W-Si-N barrier layer materials, 149
Effect of annealing rate on the crystallization process in $Ge_5Bi_{18}Se_{77}$ films, 254

Defective diamond
Growth and characterization of defective diamond films, 45
Deposition process
New method for making porous SiO_2 thin films, 124
Diamond
Porous freestanding diamond membranes with reduced pore diameter, 239
Dielectric properties
Fabrication of barium titanate thin films with a high dielectric constant by a sol–gel technique, 144
Dielectric properties of Sol–gel derived PZT(40/60)/PZT(60/40) heterolayered thin films, 244
Diethylaminopropyl triethoxysilane (DEAPTES)
The effect of catalyzing additives on Sol–gel process of formation and on the properties of modified polysiloxane layers, 108
Direct structure depth profiling
Direct structure depth profiling of polycrystalline thin films by X-ray diffraction and its application, 56
Doping
Indium doping of amorphous SiC:H films prepared by reactive magnetron co-sputtering, 189

Effective medium approximation
Growth and characterization of defective diamond films, 45
Elastic properties
Elastic properties of thin *h*-BN films investigated by Brillouin light scattering, 137
Elastic properties of hydrogen-free amorphous carbon thin films and their relation with carbon–carbon bonding, 208
Electromigration
Current induced effects in aluminum thin films, 1
Electron spin resonance
Silicon dots/clusters in silicon nitride: photoluminescence and electron spin resonance, 20
Ellipsometry
The initial oxidation of ε-Fe_2N_{1-x}: growth kinetics, 72
Simultaneous determination of the optical properties and of the structure of r.f.-sputtered ZnO thin films, 93
Epitaxy
Epitaxy of (106)-oriented $SrBi_2Ta_2O_9$ and $SrBi_2Nb_2O_9$ thin films, 52
Structural characterization of epitaxial $Cu_2Mo_6S_8$ thin films grown on *R*-cut sapphire by pulsed laser deposition, 62
Solid phase epitaxy for low pressure chemical vapor deposition Si films induced by ion implantation, 274

Fatigue characteristics
Dielectric properties of Sol–gel derived PZT(40/60)/PZT(60/40) heterolayered thin films, 244
Ferroelectric properties
A study on abnormal electric properties of lead lanthanum titanate thin films caused by excess PbO, 25
Strong substrate effect in local poling of ultrathin ferroelectric polymer films, 259
Fourier transform infrared spectroscopy
Characterization of the interfacial region of epitaxial $TlBiSe_2$ thin films by infrared spectroscopy and transmission electron microscopy, 85

Growth mechanism
Characterization of the interfacial region of epitaxial $TlBiSe_2$ thin films by infrared spectroscopy and transmission electron microscopy, 85

Hardness
Elastic properties of hydrogen-free amorphous carbon thin films and their relation with carbon–carbon bonding, 208
Heat treatment
New method for making porous SiO_2 thin films, 124
Hemicyanine
Langmuir–Blodgett films of a new hemicyanine dye, 214
Hole transport
Organic light emitting devices containing a highly substituted isoindole or polyisoindole, 218
Hydrolytic polymerization
The effect of catalyzing additives on Sol–gel process of formation and on the properties of modified polysiloxane layers, 108

Incorporation
Improvement of the thermal stability of amorphous carbon films by incorporation of nitrogen, 157
Indium
Indium doping of amorphous SiC:H films prepared by reactive magnetron co-sputtering, 189
Indium sulphide
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100
Infrared spectroscopy
Excited helium-induced CVD of a-$Si_{1-x}C_x$:H films from trimethylchlorosilane, 79
Interfaces
Mechanical behaviour of submicron multilayers submitted to microtensile experiments, 201
Interfacial reaction
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
Ion bombardment
SnO_2 thin films prepared by ion beam induced CVD: preparation and characterization by X-ray absorption spectroscopy, 113
Ion implantation
Solid phase epitaxy for low pressure chemical vapor deposition Si films induced by ion implantation, 274
Iron
The initial oxidation of ε-Fe_2N_{1-x}: growth kinetics, 72
Isoindole
Organic light emitting devices containing a highly substituted isoindole or polyisoindole, 218

Langmuir–Blodgett Films
Langmuir–Blodgett films of a new hemicyanine dye, 214

Atomic force microscopy study of cytochrome *f* (Cyt *f*) and mixed monogalactosyldiacylglycerol (MGDG)/Cyt *f* Langmuir–Blodgett films, 233
Lanthanides
A study on abnormal electric properties of lead lanthanum titanate thin films caused by excess PbO, 25
Laser ablation
Structural characterization of epitaxial $Cu_2Mo_6S_8$ thin films grown on *R*-cut sapphire by pulsed laser deposition, 62
Leakage current density
Dielectric properties of Sol–gel derived PZT(40/60)/PZT(60/40) heterolayered thin films, 244
Light emitting device
Organic light emitting devices containing a highly substituted isoindole or polyisoindole, 218
Luminescence
Luminescence behavior of $Eu(TTFA)_3$ doped Sol–gel films, 223

Metal cutting
TEM investigation of wear mechanisms during metal machining, 182
Metal-ferroelectric-insulator-semiconductor structure
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
Metal-insulator-semiconductor structure
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
Metallization
Effects of annealing on X-ray-amorphous CVD W-Si-N barrier layer materials, 149
Mechanical behaviour of submicron multilayers submitted to microtensile experiments, 201
Phase formation behavior and diffusion barrier property of reactively sputtered tantalum-based thin films used in semiconductor metallization, 264
Molecular beam epitaxy
Effect of diatomic islands on step morphological stability of a terrace edge in molecular beam epitaxy, 174
Properties of $Bi_{2+x}Sr_{2-x}CuO_{6+\delta}$ thin films obtained by MBE, 227
Monolayers
Langmuir–Blodgett films of a new hemicyanine dye, 214
Atomic force microscopy study of cytochrome *f* (Cyt *f*) and mixed monogalactosyldiacylglycerol (MGDG)/Cyt *f* Langmuir–Blodgett films, 233
Multilayers
Structure evolution in Ag/Ni multilayers grown by ultra high vacuum DC magnetron sputtering, 166
Elastic properties of hydrogen-free amorphous carbon thin films and their relation with carbon–carbon bonding, 208

Nanostructures
Silicon dots/clusters in silicon nitride: photoluminescence and electron spin resonance, 20
Nickel
Structure evolution in Ag/Ni multilayers grown by ultra high vacuum DC magnetron sputtering, 166
Nitrides
Effects of annealing on X-ray-amorphous CVD W-Si-N barrier layer materials, 149
The initial oxidation of ε-Fe_2N_{1-x}: growth kinetics, 72
Nitrogen
The initial oxidation of ε-Fe_2N_{1-x}: growth kinetics, 72
Non-aqueous medium
Non-aqueous chemical bath deposition of Sb_2S_3 thin films, 29
Nucleation
Effect of diatomic islands on step morphological stability of a terrace edge in molecular beam epitaxy, 174

Optical properties
Effect of ligands on crystal structures and optical properties of TiO_2 prepared by sol–gel processes, 67
Simultaneous determination of the optical properties and of the structure of r.f.-sputtered ZnO thin films, 93
Langmuir–Blodgett films of a new hemicyanine dye, 214
Organic layer
Organic light emitting devices containing a highly substituted isoindole or polyisoindole, 218
Organometallic complex
Luminescence behavior of $Eu(TTFA)_3$ doped Sol–gel films, 223
Oxidation
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
The initial oxidation of ε-Fe_2N_{1-x}: growth kinetics, 72
Oxides
A study on abnormal electric properties of lead lanthanum titanate thin films caused by excess PbO, 25

Pd/Ag bilayer
Thermally driven shape instabilities of Nb/Cu multilayer structures: instability of Nb/Cu multilayers, 33
Direct structure depth profiling of polycrystalline thin films by X-ray diffraction and its application, 56
Phase transitions
Surface analysis and phase transition of gel-derived VO_2 thin films, 40
Phase formation behavior and diffusion barrier property of reactively sputtered tantalum-based thin films used in semiconductor metallization, 264
Photoconductivity
Atomic force microscopy study of cytochrome *f* (Cyt *f*) and mixed monogalactosyldiacylglycerol (MGDG)/Cyt *f* Langmuir–Blodgett films, 233
Photoluminescence
Silicon dots/clusters in silicon nitride: photoluminescence and electron spin resonance, 20
Piezoelectric effect
Strong substrate effect in local poling of ultrathin ferroelectric polymer films, 259
Plasma processing and deposition
Porous freestanding diamond membranes with reduced pore diameter, 239
Pole-figure analysis
Epitaxy of (106)-oriented $SrBi_2Ta_2O_9$ and $SrBi_2Nb_2O_9$ thin films, 52

Polyisoindole
Organic light emitting devices containing a highly substituted isoindole or polyisoindole, 218
Polymers
Conduction mechanism in plasma polymerized lemongrass oil films, 249
Strong substrate effect in local poling of ultrathin ferroelectric polymer films, 259
PZT
Dielectric properties of Sol–gel derived PZT(40/60)/PZT(60/40) heterolayered thin films, 244

Raman scattering
Improvement of the thermal stability of amorphous carbon films by incorporation of nitrogen, 157
Reciprocal-space map
Epitaxy of (106)-oriented $SrBi_2Ta_2O_9$ and $SrBi_2Nb_2O_9$ thin films, 52
Reflection high energy electron diffraction
Properties of $Bi_{2+x}Sr_{2-x}CuO_{6+\delta}$ thin films obtained by MBE, 227
Remote plasma enhanced CVD
Excited helium-induced CVD of a-$Si_{1-x}C_x$:H films from trimethylchlorosilane, 79
Rietveld method
Characterisation of ZnS:Mn thin films by Rietveld refinement of Bragg–Brentano X-ray diffraction patterns, 129

Sb_2S_3 films
Non-aqueous chemical bath deposition of Sb_2S_3 thin films, 29
Scanning tunneling microscopy
Properties of $Bi_{2+x}Sr_{2-x}CuO_{6+\delta}$ thin films obtained by MBE, 227
Schottky barrier
Conduction mechanism in plasma polymerized lemongrass oil films, 249
Sensors
Atomic force microscopy study of cytochrome *f* (Cyt *f*) and mixed monogalactosyldiacylglycerol (MGDG)/Cyt *f* Langmuir–Blodgett films, 233
Silicon carbide
Excited helium-induced CVD of a-$Si_{1-x}C_x$:H films from trimethylchlorosilane, 79
Silicon dioxide
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
Silicon nitride
Silicon dots/clusters in silicon nitride: photoluminescence and electron spin resonance, 20
Silicon oxide
New method for making porous SiO_2 thin films, 124
Silver
Structure evolution in Ag/Ni multilayers grown by ultra high vacuum DC magnetron sputtering, 166
Sol–gel
Luminescence behavior of $Eu(TTFA)_3$ doped Sol–gel films, 223
Dielectric properties of Sol–gel derived PZT(40/60)/PZT(60/40) heterolayered thin films, 244
Specimen preparation
TEM investigation of wear mechanisms during metal machining, 182
Spectroscopic ellipsometry
Growth and characterization of defective diamond films, 45
Sputtering
Highly oriented ZnO thin films deposited on Ru/Si substrates, 12
Microstructure and crystallographic texture of reactively sputtered FeTaN films, 16
Characterisation of ZnS:Mn thin films by Rietveld refinement of Bragg–Brentano X-ray diffraction patterns, 129
Structure evolution in Ag/Ni multilayers grown by ultra high vacuum DC magnetron sputtering, 166
Indium doping of amorphous SiC:H films prepared by reactive magnetron co-sputtering, 189
Stress
Mechanical behaviour of submicron multilayers submitted to microtensile experiments, 201
Strongly orientated growth
Effect of annealing rate on the crystallization process in $Ge_5Bi_{18}Se_{77}$ films, 254
Structural characterization
Non-aqueous chemical bath deposition of Sb_2S_3 thin films, 29
Structural properties
Highly oriented ZnO thin films deposited on Ru/Si substrates, 12
Structural characterization of epitaxial $Cu_2Mo_6S_8$ thin films grown on *R*-cut sapphire by pulsed laser deposition, 62
Characterization of the interfacial region of epitaxial $TlBiSe_2$ thin films by infrared spectroscopy and transmission electron microscopy, 85
Simultaneous determination of the optical properties and of the structure of r.f.-sputtered ZnO thin films, 93
Sulphur dioxide
The effect of catalyzing additives on Sol–gel process of formation and on the properties of modified polysiloxane layers, 108
Superconductivity
Properties of $Bi_{2+x}Sr_{2-x}CuO_{6+\delta}$ thin films obtained by MBE, 227
Surface acoustic waves
Elastic properties of thin *h*-BN films investigated by Brillouin light scattering, 137
Surface diffusion
Effect of diatomic islands on step morphological stability of a terrace edge in molecular beam epitaxy, 174
Surface morphology
Effect of diatomic islands on step morphological stability of a terrace edge in molecular beam epitaxy, 174
Atomic force microscopy of in situ deformed nickel thin films, 194
Porous freestanding diamond membranes with reduced pore diameter, 239

Tantalum
Phase formation behavior and diffusion barrier property of reactively sputtered tantalum-based thin films used in semiconductor metallization, 264

Tantalum nitride
Phase formation behavior and diffusion barrier property of reactively sputtered tantalum-based thin films used in semiconductor metallization, 264
Tin oxide
SnO_2 thin films prepared by ion beam induced CVD: preparation and characterization by X-ray absorption spectroscopy, 113
Titanium oxide
Effect of ligands on crystal structures and optical properties of TiO_2 prepared by sol–gel processes, 67
Transmission electron microscopy
Microstructure and crystallographic texture of reactively sputtered FeTaN films, 16
Effect of ligands on crystal structures and optical properties of TiO_2 prepared by sol–gel processes, 67
Characterization of the interfacial region of epitaxial $TlBiSe_2$ thin films by infrared spectroscopy and transmission electron microscopy, 85
TEM investigation of wear mechanisms during metal machining, 182
Solid phase epitaxy for low pressure chemical vapor deposition Si films induced by ion implantation, 274
Trimethylchlorosilane
Excited helium-induced CVD of a-$Si_{1-x}C_x$:H films from trimethylchlorosilane, 79
Tungsten
Effects of annealing on X-ray-amorphous CVD W-Si-N barrier layer materials, 149

Vanadium oxide
Surface analysis and phase transition of gel-derived VO_2 thin films, 40

Wear mechanisms
TEM investigation of wear mechanisms during metal machining, 182

X-ray absorption spectroscopy
SnO_2 thin films prepared by ion beam induced CVD: preparation and characterization by X-ray absorption spectroscopy, 113
X-ray diffraction
Current induced effects in aluminum thin films, 1
Microstructure and crystallographic texture of reactively sputtered FeTaN films, 16
Thermally driven shape instabilities of Nb/Cu multilayer structures: instability of Nb/Cu multilayers, 33
Direct structure depth profiling of polycrystalline thin films by X-ray diffraction and its application, 56
Effect of ligands on crystal structures and optical properties of TiO_2 prepared by sol–gel processes, 67
Characterisation of ZnS:Mn thin films by Rietveld refinement of Bragg–Brentano X-ray diffraction patterns, 129
X-ray photoelectron spectroscopy
Surface analysis and phase transition of gel-derived VO_2 thin films, 40
Chemical bath deposition of indium hydroxy sulphide thin films: process and XPS characterization, 100

Y_2O_3
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8
Yttrium silicate
Interfacial reactions in the thin film Y_2O_3 on chemically oxidized Si(100) substrate systems, 8

Zinc oxide
Highly oriented ZnO thin films deposited on Ru/Si substrates, 12
Simultaneous determination of the optical properties and of the structure of r.f.-sputtered ZnO thin films, 93
Zinc sulphide
Characterisation of ZnS:Mn thin films by Rietveld refinement of Bragg–Brentano X-ray diffraction patterns, 129